

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of: Confirmation Number: 4104

FUKIAGE, Noriaki

Application No.: 10/812,354 Group Art Unit: 1792

Filed: March 30, 2004

Examiner: LAFOND, Ronald D.

Title: Method of Improving the Wafer to Wafer Uniformity and Defectivity of a Deposited Dielectric Film

TRANSMITTAL AND PRELIMINARY AMENDMENT WITH RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

June 5, 2008

Sir:

This paper is responsive to the Final Office Action dated December 05, 2007.

Applicants hereby petition for a Three Month Extension of Time, payment for which is made herewith, thereby extending the due date for response to June 05, 2008. The present response includes the following:

Amendments to the Specification:	None
Amendments to the Claims:	Pages 2-7
Amendments to the Abstract:	None
Amendments to the Drawings:	None
Remarks:	Pages 8-11
Attachments:	None